

Berlin, 9/17/2019

Aktuelles Experiment:

noname.rcp

Modellbeschreibung

| Number | Layer Name      | Thickness [nm] | Refr. Index<br>[632.8 nm] | Fitted |
|--------|-----------------|----------------|---------------------------|--------|
| 0      | Air             | -              | 1.000                     | no     |
| 1      | NoName0         | 137.59         | 3.010                     | yes    |
| 2      | Silicon DUV-NIR | -              | 3.874                     | no     |

Fit parameter

| Fit parameter                 | Fit result |
|-------------------------------|------------|
| [1,1] NoName0: Thickness [nm] | 137.59     |

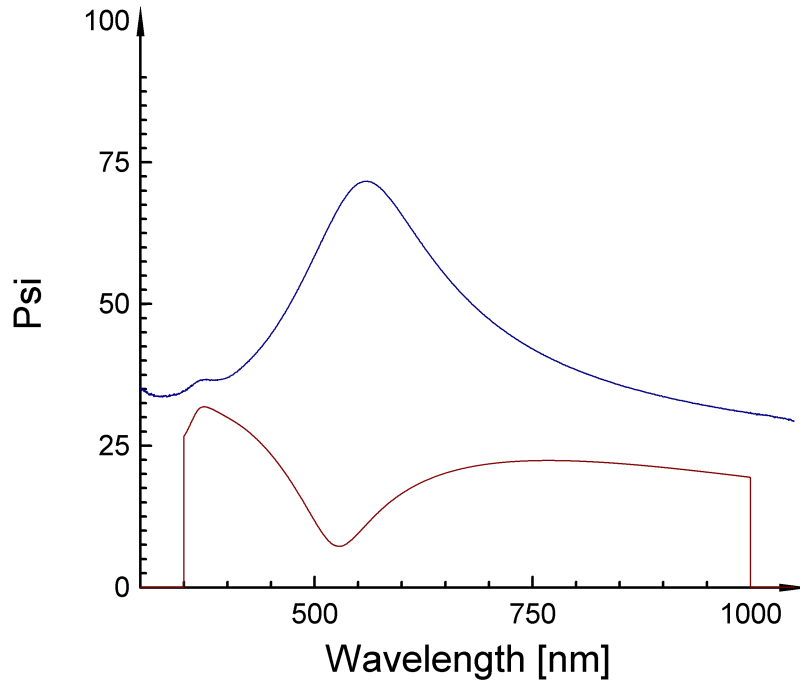
All parameter

| Parameter                      | Value   |
|--------------------------------|---------|
| [1] Wavelength [nm]            | 632.8   |
| [1] Angle [°]                  | 70.00   |
| [1] Time [s]                   | 0.0     |
| [1] Temperature [°C]           | 23.5    |
| [1] Sample rotation [°]        | 0.00    |
| [1] Depol. D0                  | 1.0000  |
| [1] Depol. D1                  | 0.0000  |
| [1] Depol. D2                  | 0.0000  |
| [1] Beam diameter              | 4.00    |
| [1] Aperture diameter          | 4.00    |
| [1,1] Thickness variation      | 10.0    |
| [1] Wavelength resolution (nm) | 0.0     |
| [1] Angle variation            | 3.0     |
| [1] Angle offset [°]           | 0.00    |
| [1] Wavelength Offset (nm)     | 0.00    |
| [1] Wavelength Linear          | 1.00000 |
| [1] Fraction Overlayer         | 1.000   |
| [1] Backside Factor            | 1.000   |
| Air: Refr. index               | 1.000   |
| Air: Absorption                | 0.000   |
| Air: N Offset                  | 0.00000 |
| Air: K Offset                  | 0.00000 |

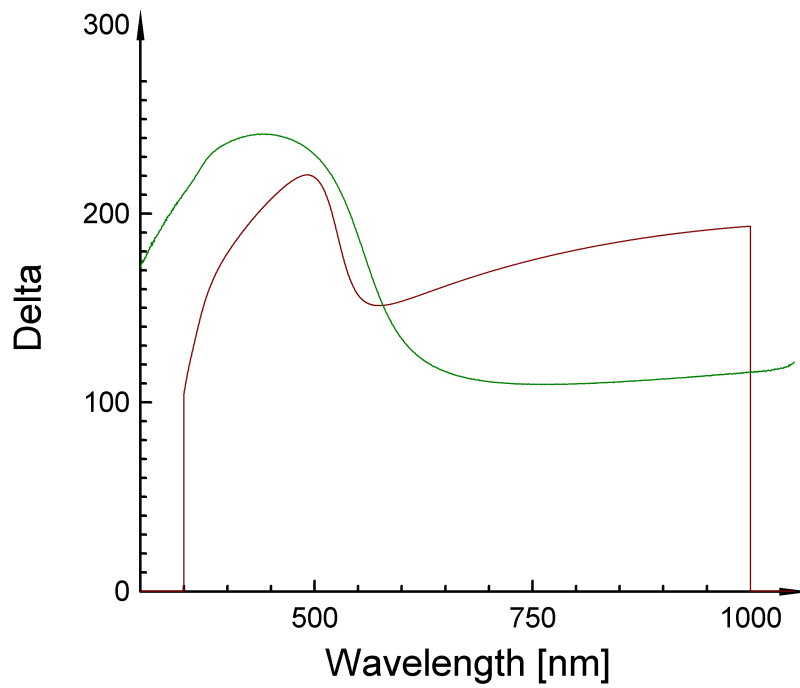
|                               |             |
|-------------------------------|-------------|
| [1,1] NoName0: Thickness [nm] | 137.59      |
| NoName0: N0                   | 3.000       |
| NoName0: N1                   | 40.0        |
| NoName0: N2                   | 0.0         |
| NoName0: K0                   | 0.000       |
| NoName0: K1                   | 0.000       |
| NoName0: K2                   | 0.000       |
| NoName0: N Offset             | 0.00000     |
| NoName0: K Offset             | 0.00000     |
| Silicon DUV-NIR: N Offset     | 0.00000     |
| Silicon DUV-NIR: K Offset     | 0.00000     |
| Pola.Pos.                     | 45.00       |
| Pola.Offs.                    | 0.00        |
| Ret.Axis                      | 0.00        |
| Ret.Phase                     | 90.00       |
| Eta                           | 1.00000     |
| Ana.Offs.                     | 0.00        |
| Ana.Offs.Lin.                 | 0.00        |
| Ana.Offs.Quadr.               | 0.00        |
| Psi Offs.                     | 0.00        |
| Psi Lin.                      | 0.00        |
| Psi Quadr.                    | 0.00        |
| Delta Offs.                   | 0.00        |
| Delta Lin.                    | 0.00        |
| Delta Quadr.                  | 0.00        |
| MSE                           | 59.78801488 |

### Measured Data

RRM001-045 / Psi, Delta / Spectral range: 300.2 nm - 1050.0 nm / Angle of incidence: 60.00 ° / 9/17/2019 2:54:54 PM



RRM001-045 / Ps ...  
—  $\Psi / \phi = 60.0^\circ$



RRM001-045 / Ps ...  
—  $\Delta / \phi = 60.0^\circ$